

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re the Application of: **Miwa KOZAWA et al.**

Group Art Unit: **1756**

Application Number: **10/720,097**

Examiner: **Daborah Chacko Davis**

Filed: **November 25, 2003**

Confirmation Number: **4454**

For: **PROCESS FOR FORMING RESIST PATTERN, SEMICONDUCTOR  
DEVICE AND FABRICATION THEREOF**

Attorney Docket Number: **032132**

Customer Number: **38834**

**AMENDMENT UNDER 37 C.F.R. §1.114**

Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

January 7, 2008

Sir:

This Submission is being filed concurrently with a Request for Continued Examination pursuant to 37 C.F.R. §1.114.

Amendments to the Claims begin on page 2 of this paper.

Remarks begin on page 8 of this paper.